What Is Claimed Is:

1	1.	An	ESD	protection	component,	comprising:
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- at least two MOS field effect transistors (FETs) of a first
- 3 conductivity type, having two gates and formed in parallel
- on a first semiconductive layer having a second conductivity
- 5 type;

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- a first well having a first conductivity type, formed on the first semiconductive layer, comprising:
 - a connecting area, formed between the MOS FETs;
 - two parallel extension areas, formed perpendicular to
 - the gates of the MOS FETs; and
 - a first doping area of the second conductivity type,
 - formed in the connecting area.
- 2. The ESD protection component in claim 1, wherein the ESD protection component further comprises a guard ring of the
- 3 second conductivity type.
- 1 3. The ESD protection circuit in claim 2, wherein the first
- 2 conductive layer is connected to a power supply through the
- 3 guarding ring.
- 1 4. The ESD protection circuit in claim 1, wherein the first well
- is separated from the drains of the MOS FETs.
- 5. The ESD protection circuit in claim 1, wherein each of the MOS FETs has a source region of the first conductivity type, coupled to a power rail.

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- 6. The ESD protection circuit in claim 1, wherein the first well is coupled to a pad through the extension areas.
- 7. The ESD protection circuit in claim 1, wherein the first doping region is coupled to a pad.
- 8. The ESD protection circuit in claim 1, wherein each of the MOS FETs has a drain region of the first conductivity type coupled to a pad.
 - 9. An ESD protection component, comprising:
 - at least two MOS field effect transistors (FETs) of a first conductivity type, comprising:
 - two gates, formed in parallel on a first semiconductive layer having a second conductivity type;
 - two sources of the first conductivity type, coupled to a power supply; and
- 8 two drains of the first conductivity type;
- a first well having a first conductivity type, formed on the first semiconductive layer, comprising:
- a connecting area, formed between the MOS FETs;
- Two parallel extension areas, formed perpendicular to the gates of the MOS FETs; and
- a first doping area of the second conductivity type,
- formed in the connecting area, and coupled to a pad; and
- a guard ring of the second conductivity type, formed
- on the first semiconductive layer, coupled to the power
- supply;
- wherein the firsPt well is coupled to the pad through the extension areas.